填充等离子体的介质契伦柯夫脉塞

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摘 要 利用自洽线性场理论, 普遍讨论了电子在扰动场作用下的三维扰动, 进而分别对 薄环形相对论电子注和实心相对论电子注在填充等离子体的介质筒慢波波导中激励的契伦柯 夫辐射进行了详细的分析, 导出了其色散方程和波增长率, 分析表明注波互作用是由于慢波系 统中的波导模与电子注模耦合所致, 填充等离子体后能大大提高注波互作用效率, 并详细计算 和分析了等离子体密度和电子注半径对波增长率的影响。

关键词 薄环形电子注 实心电子注 等离子体 介质筒 慢波波导 契伦柯夫辐射

ABSTRACT By use of the self- consistent linear field theory, 3D perturbation of electrons affected by the perturbed electrom agnetic fields is generally discussed And Cherenkov radiations excited by a thin annular relativistic electron beam and a solid relativistic electron beam in a plasma- filled, dielectric lined slow - wave waveguide are analysed in detail, respectively. The dispersion equations of the beam - wave interaction are derived. It's clearly show n that the beam - wave interaction results from the coupling of the TM mode in the plasma- filled, dielectric lined slow - wave waveguide to the beam mode via the electron beam. Finally, the grow th rates of wave are obtained, and the effect of plasma density and the electron beam radius on the grow th rate of the wave is calculated and discussed

KEY WORDS thin annular electron beam, solid electron beam, plasma, dielectric liner, slow - wave waveguide, Cherenkov radiations

0 引 言

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在高功率相对论微波器件中充填适当密度的背景等离子体可有效地提高器件的注波互作 用效率、工作频率和输出功率^[1~3]。目前有关这方面的实验主要集中体现在两类高功率微波器 件中,一是介质契伦柯夫脉塞^[2],另一是相对论返波管^[3]。代表性的实验有:1987年,俄罗斯用 0.9kA、0.4MV相对论电子注,由等离子体契伦柯夫脉塞产生了0.1GW的微波,效率为 20%^[1];美国加州大学Davis分校利用等离子体契伦柯夫脉塞作放大器,得到了输出功率达 GW 水平的微波,效率大于10%^[2];而最具影响的实验是美国马里兰大学的研究小组将等离子 体注入相对论返波管中,得到了输出功率600MW,效率达40%的微波输出,效率比未充等离子 体的同类器件提高了近8倍^[3]。

令人振奋实验结果的取得,推动了理论研究的深入发展^[4~9];目前的理论研究几乎都只考虑了电子的一维扰动;本文利用线性自洽场理论,普遍讨论了电子在扰动场作用下的三维扰

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动,在此基础上,对目前在等离子体介质契伦柯 夫脉塞中常用的两种相对论电子注,薄环形相 对论电子注产生的注波互作用进行了详细的分 析与讨论。

1 扰动场作用下的电子三维扰动

设平衡速度为 v_{0} , 平衡密度为 n_{0} 的相对论 电子注沿对称轴 z 穿过如图1所示的填充平衡 密度为 $n_{p_{0}}$ 的等离子体介质筒慢波波导。设电子 注的密度 n 和速度 v 可表为,



Fig. 1 Plasm a-filled, dielectric

lined slow wave waveguied

图1 填充等离子体的介质筒慢波波导

$$n = n_0 + \delta n$$

$$v = v_0 e_z + \delta v$$
(1)

这里, $\delta_n \ll n_0$, $\delta_v \ll v_0$; 由此就可将连续性方程和运动方程分别线性化为

$$\left(\frac{\partial}{\partial t} + v_0 \frac{\partial}{\partial z}\right) \delta n + n_0 \nabla \cdot \delta v = 0$$
⁽²⁾

$$\left(\frac{\partial}{\partial t} + v_0 \frac{\partial}{\partial z}\right) \delta v = - \frac{e}{\gamma_{om 0}} \left[\left(\vec{I} - \beta_0^2 e_z e_z\right) \cdot \delta E + v_0 e_z \times \delta B \right]$$
(3)

式中, $e \, n_m$ 。分别为电子的电量和静止质量; $\beta_0 = v_0/c$; $\lambda = (1 - \beta_0^2)^{-1/2}$; $\delta E \, n \, \delta B \,$ 分别为扰动 电场和磁场; I为单位张量; e_z 为轴向单位矢量。这里我们不考虑纵向引导磁场的作用。设系统 具有角向对称, 且所有的扰动量可表示为如下的变化形式

$$\delta F(r, z, t) = \delta f(r) e^{j(\omega - kz)}$$
(4)

式中, ω 和 k 分别为角频率和纵向波数。这样采用柱坐标系 (r, Q_z), 由方程 (3) 就可得电子注上的扰动速度为

$$\delta_{V_r} = - \frac{e}{\gamma_{\sigma m_0}\omega} (-j \delta E_r + \frac{v_0}{\omega - kv_0} \frac{\partial \delta E_z}{\partial r})$$

$$\delta_{V\varphi} = j \frac{e \delta E_{\varphi}}{\gamma_{\sigma m_0}\omega}$$

$$\delta_{V_z} = j \frac{e \delta E_z}{\gamma_{\sigma m_0}^3 (\omega - kv_0)}$$
(5)

由方程(2)就可得电子注上的扰动密度为

$$\delta n = j \frac{n_0 e}{\gamma_{0m_0} (\omega - k_{v_0})^2} \left\{ \frac{k \delta E_z}{\gamma_0^2} - \frac{1}{\omega} \left[-j (\omega - k_{v_0}) \right] \right\}$$

$$\cdot \frac{1}{r} \frac{\partial}{\partial r} (r \delta E_r) + v_0 \frac{1}{r} \frac{\partial}{\partial r} (r \frac{\partial \delta E_z}{\partial r}) \left]$$
(6)

由方程

$$\delta J = -e(\delta n v_0 + n_0 \delta v) \tag{7}$$

就可得电子注上的三维扰动电流密度

$$\delta J_{r} = \frac{n_{0}e^{2}}{\gamma_{0m}} \left[-j \, \delta E_{r} + \frac{\nu_{0}}{\omega} - \frac{\partial \delta E_{z}}{\beta \nu_{0}} \right]$$
$$\delta J_{\varphi} = -j \frac{n_{0}e^{2} \delta E_{\varphi}}{\gamma_{0m}} \frac{\partial \delta E_{z}}{\partial \omega}$$

$$\delta J_{z} = -j \frac{n_{0}e^{2}}{\mathcal{Y}_{0}m_{0}(\omega - kv_{0})^{2}} \left\{ \frac{\omega}{\mathcal{Y}_{0}^{2}} \delta E_{z} - \frac{v_{0}}{\omega} \left[-j(\omega - kv_{0}) \cdot \frac{1}{r} \frac{\partial}{\partial r} (r \delta E_{r}) + v_{0} \frac{1}{r} \frac{\partial}{\partial r} (r \frac{\partial \delta E_{z}}{\partial r}) \right] \right\}$$

$$(8)$$

等离子体中电子在扰动场作用下的三维扰动,只要在以上的推导中令 $v_0=0$,就可得到等离子体中电子的扰动速度 δ_{v_p} ,扰动密度 δ_{n_p} 和三维扰动电流密度 δ_{v_p} ,分别为

$$\delta v_p = j \frac{e \delta E}{m_0 \omega} \tag{9}$$

$$\delta n_p = j \frac{n_{p0}e}{m_0 \omega^2} \{ k \, \delta E_z + j \, \frac{1}{r} \, \frac{\partial}{\partial r} (r \, \delta E_r) \}$$
(10)

$$\delta U_{p} = -j \frac{n_{p} o e^{2}}{m_{0} \omega} \delta E$$
(11)

这里下标 p 表示为等离子体的参量。因此, 扰动电磁场对电子的作用所引起的总扰动密度和 总扰动电流密度就为上述二部分之和。

2 相对论电子注的扰动电流和电荷密度

利用上述电子注在扰动电磁场作用下的扰动速度、扰动电流密度和扰动密度的普遍表达式,分别求薄环形相对论电子注和实心相对论电子注的扰动电流密度和扰动电荷密度。

(1) 薄环形相对论电子注的扰动电流和电荷密度

设薄环形相对论电子注的厚度非常薄,满足条件 ΔR _b/R _b << 1,这样此薄环形电子注的平衡 密度就可以用下方程描述,其中, R _b 和 ΔR _b 分别为电子注的半径和厚度。

$$n_0(r) = n_{b0} \Delta R_b \delta(r - R_b)$$
(12)

由于已假设环形电子注非常薄,因而只在 *r= R*,处有贡献,这样就可忽略横向扰动场对电子注的作用;将方程(12)代入(8),就可得此电子注上的扰动电流密度近似为

$$\delta I - j \frac{\omega_b^2}{\gamma_0^2} \frac{\omega \epsilon_0 \Delta R_b}{(\omega - k v_0)^2} \delta(r - R_b) (e_z \bullet \delta E) e_z$$
(13)

式中, $\alpha_{i}^{2} = \frac{n_{boe}^{2}}{\gamma_{m_{0}}G_{0}}$; 65为自由空间介电常数。将方程(12)代入方程(6), 就可得电子注上的扰动电 荷密度近似为

$$\delta \rho - j \frac{\omega^2}{\gamma_0^2} \frac{k \epsilon_0 \Delta R_b}{(\omega - k v_0)^2} \delta(r - R_b) e_z \bullet \delta E$$
(14)

(2) 实心相对论电子注的扰动电流和电荷密度

对于实心相对论电子注,其平衡密度可用下面方程描述

$$n_0(r) = n_{b0}H(r - R_b)$$
(15)

式中H 为阶跃函数。将此方程代入(8),就可得此电子注上的扰动电流密度为

$$\delta J_{r} = \frac{\omega \xi}{\omega} H (r - R_{b}) \begin{bmatrix} -j \delta E_{r} + \frac{v_{0}}{\omega - kv_{0}} \frac{\partial \delta E_{z}}{\partial r} \end{bmatrix}$$
$$\delta J_{\varphi} = -j \frac{\omega \xi}{\omega} H (r - R_{b}) \delta E_{\varphi}$$
$$\delta J_{z} = -j \frac{\omega \xi}{(\omega - kv_{0})^{2}} H (r - R_{b}) \{ \frac{\omega}{\gamma_{0}^{2}} \delta E_{z} - \frac{v_{0}}{\omega} [-j (\omega - \omega) \} \}$$

$$kv_{0}) \frac{1}{r} \frac{\partial}{\partial r} (r \delta E_{r}) + v_{0} \frac{1}{r} \frac{\partial}{\partial r} (r \frac{\partial \delta E_{z}}{\partial r})] \}$$
(16)

将方程(15)代入(6),就可得电子注上的扰动电荷密度为

$$\delta \rho = -j \frac{\omega_{k}^{2} \epsilon_{0}}{(\omega - kv_{0})^{2}} H (r - R_{b}) \left\{ \frac{\beta \delta E_{z}}{y_{0}^{2}} - \frac{1}{\omega} \left[-j (\omega - kv_{0}) \frac{1}{r} \frac{\partial}{\partial r} (r \delta E_{r}) + v_{0} \frac{1}{r} \frac{\partial}{\partial r} (r \frac{\partial \delta E_{z}}{\partial r}) \right] \right\}$$
(17)

3 色散方程

为了使电子与场产生有效互作用,使电子在纵向群聚而将能量交给场,则其场必须具有纵向分量;因此这里就可只讨论电子与 TM 模的互作用。由麦克斯韦方程组,很容易得到扰动电场满足的波方程为

$$\nabla^{2} \delta E - \nabla (\nabla \cdot \delta E) + \frac{\omega^{2}}{c^{2}} \delta E = j \omega \mu_{0} \delta J$$
(18)

式中, µ₀为自由空间磁导率。将上节求得的各扰动电流密度和电荷密度代入上面的方程中, 分区(见图1)求解, 就可推得其描述注波互作用的色散方程。

(1) 薄环形相对论电子注的注波互作用色散方程

将方程(11)和(13)代入波方程(18),就可得纵向扰动电场满足的方程为

$$\frac{1}{r}\frac{\partial}{\partial r}\left(r\frac{\partial \delta E_z}{\partial r}\right) - p^2 \delta E_z = -\frac{\omega_z^2}{y_0^2}\frac{p^2}{1-\frac{\omega_z^2}{\omega_z^2}}\frac{\Delta R_b \delta(r-R_b)}{(\omega-kv_0)^2}\delta E_z$$
(19)

式中, $p^2 = k^2 - \frac{\omega^2}{c^2} (1 - \frac{\omega^2}{\omega^2}); q^2 = \frac{\omega^2}{c^2} \epsilon - k^2; \quad m \omega^2 = \frac{n_{\mu 0} e^2}{m_{0} \epsilon}; \epsilon$ 为介质筒的相对介电常数。将方程 (19)的两边沿电子注作径向积分, 就可得

$$\lim_{\epsilon \to 0} \frac{\partial \delta E_{z}}{\partial r} \bigg|_{R_{b^{-}}\epsilon}^{R_{b^{+}}\epsilon} = - \frac{\omega^{2}}{\gamma_{0}^{2}} \frac{p^{2}}{1 - \frac{\omega^{2}}{\omega^{2}}} \frac{\Delta R_{b}}{(\omega - kv_{0})^{2}} \delta E_{z}(R_{b})$$
(20)

由此可见,薄环形电子注的存在致使径向电场在其电子注所在的位置不连续而产生跳变,方程 (20)为跳变条件,因此薄环形电子注的作用就完全由此跳变条件来描述。这样由方程(18)和 (19),就可将纵向扰动电场的解表示为以下形式

$$\delta E_{z} = \begin{cases} A \ I_{0}(p \ r) & (0 \ r \ R_{b}) \\ B \ I_{0}(p \ r) + \ CK_{0}(p \ r) & (R_{b} < r \ a) \\ D \ J_{0}(q \ r) + \ EY_{0}(q \ r) & (a < r \ b) \end{cases}$$
(21)

式中, I₀和 K₀分别为零阶第一类和第二类虚宗量贝塞尔函数; J₀和 Y₀分别为零阶第一类和第 二类贝塞尔函数。利用边界条件和跳变条件(20), 消去待定系数, 就可得薄环形相对论电子注 的注波互作用色散方程为

$$\frac{(1 - \omega_{b}^{2}/\omega_{c}^{2})I_{1}(pa)B(qb,qa) - \frac{p \cdot \epsilon}{q}I_{0}(pa)A(qb,qa)}{(1 - \omega_{b}^{2}/\omega_{c}^{2})K_{1}(pa)B(qb,qa) + \frac{p \cdot \epsilon}{q}K_{0}(pa)A(qb,qa)} = \frac{\frac{\omega_{b}^{2} \cdot p \Delta R_{b}}{\gamma_{0}^{2}(\omega - kv_{0})^{2}}I_{0}^{2}(pR_{b})}{(1 - \frac{\omega_{b}^{2}}{\omega_{c}^{2}})^{2}C(pR_{b},pR_{b}) - \frac{\omega_{b}^{2} \cdot p \Delta R_{b}}{\gamma_{0}^{2}(\omega - kv_{0})^{2}}I_{0}(pR_{b})K_{0}(pR_{b})}$$
(22)

这里已定义 $A(x,y) = J_0(x)Y_1(y) - J_1(y)Y_0(x), B(x,y) = J_0(x)Y_0(y) - J_0(y)Y_0(x),$ $C(x,y) = I_0(x)K_1(y) + I_1(y)K_0(x)$

(2) 实心相对论电子注的注波互作用色散方程

利用与以上相同的推导,将实心相对论电子注的扰动电流密度和等离子体的扰动电流密 度代入波方程(19)中,分区求解可得纵向扰动电场满足的方程为

$$\begin{cases} \frac{1}{r} \frac{\partial}{\partial r} \left(r \frac{\partial \delta E_z}{\partial r} \right) - T^2 \delta E_z = 0 & (0 \quad r \quad R_b) \\ \frac{1}{r} \frac{\partial}{\partial r} \left(r \frac{\partial \delta E_z}{\partial r} \right) - p^2 \delta E_z = 0 & (R_b < r \quad a) \\ \frac{1}{r} \frac{\partial}{\partial r} \left(r \frac{\partial \delta E_z}{\partial r} \right) + q^2 \delta E_z = 0 & (a < r \quad b) \end{cases}$$
(23)

式中

$$T^{2} = U \left[k^{2} - \frac{\omega^{2}}{c^{2}} \left(1 - \frac{\omega^{2}}{\omega^{2}} - \frac{\omega^{2}}{\omega^{2}} \right) \right]$$
(24)

$$U = 1 + \frac{v_0^2 \omega \omega'/c^2 \omega (\omega - kv_0)^2}{1 - \omega^2/\lambda_0^2 (\omega - kv_0)^2 - (\omega^2/\omega^2) [1 + v_0^2 \omega^2/c^2 (\omega - kv_0)^2]}$$
(25)

方程(23)的解仍可表示为方程(21)的形式。利用边界条件,就可推得实心相对论电子注的注波 互作用色散方程为

$$\frac{I_{0}(TR_{b})}{I_{1}(TR_{b})} = S \frac{p}{T} \left\{ \begin{array}{c} 1 - \frac{\omega_{b}^{2}}{\omega_{c}^{2}} B(qb,qa)C(pR_{b},pa) + \frac{p \epsilon}{q} A(qb,qa)D(pR_{b},pa) \\ 1 - \frac{\omega_{b}^{2}}{\omega_{c}^{2}} B(qb,qa)E(pR_{b},pa) + \frac{p \epsilon}{q} A(qb,qa)C(pa,pR_{b}) \end{array} \right.$$
(26)

式中

式中

$$S = U \left[1 - \frac{\omega_{p}^{2}}{\gamma_{0}^{2}} (\omega - kv_{0})^{2} - \frac{(v_{0}^{2}/c^{2})}{\omega_{p}^{2}} (\omega_{p}^{2} \omega_{p}^{2}/\omega_{k}v_{0}(\omega - kv_{0})^{2} \right],$$

$$D(x, y) = I_{0}(x) K_{0}(y) - I_{0}(y) K_{0}(x), E(x, y) = I_{1}(x) K_{1}(y) - I_{1}(y) K_{1}(x)$$

4 波增长率

为了得到注波互作用产生的波增长率,我们将薄环形相对论电子注的注波互作用色散方 程稍加整理重新写为如下形式

$$\begin{bmatrix} I_{1}(p a)B(qb, qa) - \frac{p}{q} \frac{\epsilon}{1 - \frac{\omega_{1}^{2}}{\omega^{2}}} I_{0}(p a)A(qb, qa) \end{bmatrix} \bullet$$

$$\bullet (\omega - kv_{0})^{2} = \frac{\omega_{1}^{2}}{y_{0}^{2}} \frac{-p \Delta R_{b}}{(1 - \frac{\omega_{1}^{2}}{\omega^{2}})^{2}} XI_{0}(pR_{b})$$

$$(27)$$

$$\chi = \frac{(1 - \frac{\alpha t}{\omega})B(qb, qa)C(pR_b, pa) + \frac{p}{q}}{C(pR_b, pR_b)} (qb, qa)D(pR_b, pa)}$$
(28)

若令ω 0(即无电子注),则由方程(27)可得

$$F_{1} = I_{1}(p a)B(qb, qa) - \frac{p}{q} \frac{\epsilon}{1 - \frac{\omega^{2}}{\omega^{2}}} I_{0}(p a)A(qb, qa) = 0$$
(29)

$$\begin{cases} F_2 = \omega - kv_0 = 0 \\ 2005 Tringhua Tongfang Optical Disc Co. Ltd. All rights reserved \end{cases}$$

第一个方程就是填充等离子体的介质筒慢波波导 TM $_{\omega}$ 模的色散方程^[10], 而第二个方程就是 电子注模的色散方程; 此方程就清楚地表明, 契伦柯夫辐射来源于慢波系统中的波导模与电子 注模的耦合, 且其耦合强度与电子注的密度成正比; 当同时满足方程(29)时, 注波互作用就可 产生契伦柯夫辐射, 电子将能量交给波, 使波得到增长。因此方程(29)就是产生契伦柯夫辐射 的同步条件。设由方程(29)解得的工作频率为 ω , 令 $\omega = \omega + \delta \omega$, 其中 $\delta \omega \ll \omega$, 则由耦合方程 (27)就可求得薄环形相对论电子注产生的波增长率 *G* 为

$$G = \frac{\sqrt{3}}{2} \left[\frac{\omega_{\ell}^{2}}{\gamma_{0}^{2}} \frac{p \Delta R_{b}}{(1 - \omega_{\ell}^{2})^{2}} \frac{I_{0}(pR_{b})}{\partial w} \chi \right]^{1/3}$$
(30)

其中

$$\frac{\partial F_{1}}{\partial w} = 2 \frac{\omega_{L}^{2}}{\omega^{3}} - \frac{\omega \omega A_{-}(qb, qa)}{c^{2}q^{2}} \frac{I_{0}(pa)}{B_{-}(qa, qb)} \frac{I_{0}(pa)}{I_{1}(pa)} \{2 \frac{q}{p} + \epsilon \frac{p}{q} + qa[\frac{I_{1}(pa)}{I_{0}(pa)} - \frac{I_{0}(pa)}{I_{1}(pa)}]$$

$$+ \epsilon_{p} \left[\frac{qBW_{-}(qa, qb) - qaB_{-}(qa, qb) - A_{-}(qb, qa)}{qA_{-}(qb, qa)} + \frac{bA_{-}(qa, qb) - aA_{-}(qb, qa)}{B_{-}(qa, qb)}\right] \}$$

$$W_{-}(x, y) = J_{1}(x)Y_{1}(y) - J_{1}(y)Y_{1}(x)$$

对于实心相对论电子注,利用 ω kvo 0,也可将其色散方程(26)近似表示为

$$[I_{1}(pa)B(qb,qa) - \frac{p}{q} \frac{\epsilon}{1 - \frac{\omega_{b}^{2}}{\omega^{2}}} I_{0}(pa)A(qb,qa)](\omega - kv_{0})^{2} = \frac{\omega_{b}^{2}}{\gamma_{0}^{2}} \frac{pX_{s}}{1 - \frac{\omega_{b}^{2}}{\omega^{2}}} I_{1}(TR_{b})$$
(31)

式中

$$X_{s} = \frac{(1 - \frac{\Delta b}{\omega^{2}})B(qb, qa)C(pR_{b}, pa) + \frac{p}{q}}{TI_{0}(TR_{b})K_{1}(pR_{b}) + pI_{1}(TR_{b})K_{0}(pR_{b})}$$
(40)

进行与上面相同的推导,由方程(31)就可求得实心电子注产生的波增长率 G。

$$G_{s} = \frac{\sqrt{-3}}{2} \left[\frac{\omega_{k}^{2}}{\gamma_{0}^{2}} \frac{-p \chi_{s}}{1 - \omega_{k}^{2}} \frac{I_{\perp}(TR_{b})}{\partial \omega} \right]^{1/3}$$
(41)

5 计算与讨论

关于背景等离子体密度对填充等离子体的介质筒慢波波导中 TM 。 模色散特性的影响已 在文献[10]中作了详细的讨论,因此这里我们主要讨论等离子体密度和电子注半径对波增长 率的影响。图2和图3分别给出了等离子体密度对薄环形电子注和实心电子注产生的波增长率 的影响,可见在给定的各参量下,波增长率随等离子体密度的提高而增加;这就从理论上证明 了背景等离子体确实可增强注波互作用,与实验证实的结果一致^[1-3]。图4和图5分别给出了电 子注半径对薄环形电子注和实心电子注产生的波增长率的影响,可见随着电子注半径增加而 向介质筒内表面贴近时,其波增长率随之增加,这是因为纵向电场在介质筒的内表面上分布最 大^[10],所以当电子注靠近介质筒的内表面时,由于纵向电场的增加而加强了其注波互作用,故 其波增长率增加。因此,在设计实际器件时,电子注应尽量靠近介质筒的内表面穿过。



Fig 2The effect of the plasma density onthe grow th rate for the annular electron beam.图2等离子体密度对环形注产生的波增长率的影响



Fig 4 The effect of beam radius on the grow th rate for the annular electron beam. 图4 环形电子注半径对波增长率的影响



Fig 3 The effect of the plasma density on the grow th rate for the solid electron beam.图3 等离子体密度对实心注产生的波增长率的影响



Fig 5 The effect of beam radius on the grow th rate for the solid electron beam. 图5 实心电子注半径对波增长率的影响

参考文献

- 1 Kuzelev M V, et al Sov J Plasn a Phys, 1987, 13(1): 793
- 2 De Groot J S, Stone R A, and Rogers J H. SPIE, 1988, 873: 37
- 3 Carmel Y, et al IEEE T rans on Plasn a Science, 1990, 18(3): 497
- 4 Camel Y, et al Phys Rev Lett, 1989, 62(20): 2389
- 5 Kosai H, Garate E, and Fisher A. SPIE, 1990, 1226: 191
- 6 Botton M and Ron Am iram. Phys Fluids, 1992, B4(7): 1979
- 7 Peter W and Garate E. Phys Rev, 1992, A45(12): 8833
- 8 Weatherall James C and M ain William. Phys Fluids, 1992, B4(7): 1953
- 9 Choyal Y and M aheshwari K P. Phys Plasmas, 1994, 1(1): 171
- 10 吴坚强, 熊彩东, 刘盛纲 电子科技大学学报, 1995, 24(3): 277

PLASMA-FLLED DIELECTRIC CHERENKOVMASER

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Recent experiments demonstrated that injection of a background plasma into the slow - wave structure of the high- power microw ave devices greatly enhanced the beam - wave interaction efficiency, the operation frequency and the microw ave output power. In this paper, we present a self- consistent and relativistic field theory of the dielectric Cherenkov maser by solution of the relativistic fluid equations and M axwell's equations in a configuration that consists of the propagation of an axial relativistic electron beam with plasmafilled a plasma-filled annular dielectric liner enclosed by a loss- free conducting wall. First, the electron 3D perturbation affected by the perturbed electrom agnetic fields is generally evaluated by solution of the relativistic fluid equations. Then the perturbed current and charge densities of the thin annular relativistic electron beam and the solid relativistic electron beam are obtained respectively. The dispersion equations for the thin annular relativistic electron beam and the solid relativistic electron beam with the plasmafilled, dielectric lined slow - wave waveguide are derived, respectively. Solutions of the dispersion equations are discussed and the grow th rates of the wave are obtained. Finally, the effects of the background plasma density and the beam radius on the grow th rates of the wave are calculated and discussed

It's clearly shown that the beam - wave interaction in the slow - wave waveguide results from the coupling of the TM mode in the plasma- filled, dielectric lined slow - wave waveguide to the beam mode via the electron beam and the coupling is proportional to the density of the electron beam. It was theoretically demonstrated that injecting plasma into the dielectric lined waveguide could effectively enhance the beam - wave interaction efficiency of the dielectric Cherenkov maser. The results offered in this paper have provided theoretical basis for further engineering design of devices